



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Group Art Unit: 1762

Yonhua Tzeng

Examiner: Stouffer, Kelly M.

Serial No.: 10/772,740

Filed: February 5, 2004

AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION (RCE)

For: **METHOD OF PLASMA** 

ENHANCED CHEMICAL VAPOR DEPOSITION OF DIAMOND USING METHANOL-BASED

**SOLUTIONS** 

162 North Wolfe Road Sunnyvale, California 94086

(408) 530-9700

Customer No.: 28960

Mail Stop RCE

**Commissioner for Patents** 

P.O. Box 1450

Alexandria, Virginia 22313-1450

## **AMENDMENTS**

Sir:

Please amend the subject application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.